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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.
09/412,512	10/05/1999	SHUNPEI YAMAZAKI	0756-2046	9755

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EXAMINER

BOOTH, RICHARD A

ART UNIT PAPER NUMBER

2812

DATE MAILED: 02/14/2002

Please find below and/or attached an Office communication concerning this application or proceeding.

Office Action Summary

Application No.

09/412,512

Inventor(s)

YAMAZAKI, SHUNPEI

Examiner

Richard A. Booth

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-- The MAILING DATE of this communication appears on the cover sheet with the correspondence address --

Period for Reply

A SHORTENED STATUTORY PERIOD FOR REPLY IS SET TO EXPIRE 3 MONTH(S) FROM THE MAILING DATE OF THIS COMMUNICATION.

- Extensions of time may be available under the provisions of 37 CFR 1.136(a). In no event, however, may a reply be timely filed after SIX (6) MONTHS from the mailing date of this communication.
- If the period for reply specified above is less than thirty (30) days, a reply within the statutory minimum of thirty (30) days will be considered timely.
- If NO period for reply is specified above, the maximum statutory period will apply and will expire SIX (6) MONTHS from the mailing date of this communication.
- Failure to reply within the set or extended period for reply will, by statute, cause the application to become ABANDONED (35 U.S.C. § 133).
- Any reply received by the Office later than three months after the mailing date of this communication, even if timely filed, may reduce any earned patent term adjustment. See 37 CFR 1.704(b).

Status

- 1) ☒ Responsive to communication(s) filed on 31 January 2002.
- 2a) ☐ This action is **FINAL**. 2b) ☒ This action is non-final.
- 3) ☐ Since this application is in condition for allowance except for formal matters, prosecution as to the merits is closed in accordance with the practice under *Ex parte Quayle*, 1935 C.D. 11, 453 O.G. 213.

Disposition of Claims

- 4) ☒ Claim(s) 14-19 and 31-46 is/are pending in the application.
- 4a) Of the above claim(s) _____ is/are withdrawn from consideration.
- 5) ☐ Claim(s) _____ is/are allowed.
- 6) ☒ Claim(s) 14-19 and 31-46 is/are rejected.
- 7) ☐ Claim(s) _____ is/are objected to.
- 8) ☐ Claim(s) _____ are subject to restriction and/or election requirement.

Application Papers

- 9) ☐ The specification is objected to by the Examiner.
- 10) ☐ The drawing(s) filed on _____ is/are: a) ☐ accepted or b) ☐ objected to by the Examiner.
- Applicant may not request that any objection to the drawing(s) be held in abeyance. See 37 CFR 1.85(a).
- 11) ☐ The proposed drawing correction filed on _____ is: a) ☐ approved b) ☐ disapproved by the Examiner.
- If approved, corrected drawings are required in reply to this Office action.
- 12) ☐ The oath or declaration is objected to by the Examiner.

Priority under 35 U.S.C. §§ 119 and 120

- 13) ☐ Acknowledgment is made of a claim for foreign priority under 35 U.S.C. § 119(a)-(d) or (f).
- a) ☐ All b) ☐ Some * c) ☐ None of:
1. ☐ Certified copies of the priority documents have been received.
2. ☐ Certified copies of the priority documents have been received in Application No. _____.
3. ☐ Copies of the certified copies of the priority documents have been received in this National Stage application from the International Bureau (PCT Rule 17.2(a)).
- * See the attached detailed Office action for a list of the certified copies not received.
- 14) ☐ Acknowledgment is made of a claim for domestic priority under 35 U.S.C. § 119(e) (to a provisional application).
- a) ☐ The translation of the foreign language provisional application has been received.
- 15) ☐ Acknowledgment is made of a claim for domestic priority under 35 U.S.C. §§ 120 and/or 121.

Attachment(s)

- 1) ☒ Notice of References Cited (PTO-892)
- 2) ☐ Notice of Draftsperson's Patent Drawing Review (PTO-948)
- 3) ☐ Information Disclosure Statement(s) (PTO-1449) Paper No(s) _____
- 4) ☐ Interview Summary (PTO-413) Paper No(s). _____
- 5) ☐ Notice of Informal Patent Application (PTO-152)
- 6) ☐ Other: _____

DETAILED ACTION

Continued Examination Under 37 CFR 1.114

A request for continued examination under 37 CFR 1.114, including the fee set forth in 37 CFR 1.17(e), was filed in this application after final rejection. Since this application is eligible for continued examination under 37 CFR 1.114, and the fee set forth in 37 CFR 1.17(e) has been timely paid, the finality of the previous Office action has been withdrawn pursuant to 37 CFR 1.114. Applicant's submission filed on 1-31-02 has been entered.

Claim Rejections - 35 USC § 103

The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:

(a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negated by the manner in which the invention was made.

Claim 14 is rejected under 35 U.S.C. 103(a) as being unpatentable over Zhang, U.S. Patent 5,236,850 in view of Kobayashi et al., U.S. Patent 6,146,930.

Zhang is applied as in the previous office action in the rejection of claim 14 under 35 USC 102(b) but lacks anticipation of a plastic substrate.

Kobayashi discloses that TFTs can typically be formed on plastic substrates (see column 7, lines 4-9). In view of this disclosure, it would have been obvious to one of ordinary skill in the art at the time the invention was made to form the device in Zhang

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on a plastic substrate as taught by Kobayashi et al. because Kobayashi et al. discloses this to be typical device formation.

Claims 15, 17-18, 33, 35-36, and 41-44 are rejected under 35 U.S.C. 103(a) as being unpatentable over Liu et al., U.S. Patent 5,147,826 in view of Zhang, U.S. Patent 5,236,850 and further in view of Kobayashi et al., U.S. Patent 6,146,930.

Liu in view of Zhang et al. is applied as in the previous rejection but both references lack anticipation of a plastic substrate.

Kobayashi discloses that TFTs can typically be formed on plastic substrates (see column 7, lines 4-9). In view of this disclosure, it would have been obvious to one of ordinary skill in the art at the time the invention was made to form the device in Liu et al. on a plastic substrate as taught by Kobayashi et al. because Kobayashi et al. discloses this to be typical device formation.

Claims 16, 19, 37, and 39-40 are rejected under 35 U.S.C. 103(a) as being unpatentable over Yamazaki et al., U.S. Patent 5,773,227 in view of Zhang, U.S. Patent 5,236,850 and further in view of Kobayashi et al., U.S. Patent 6,146,930.

Yamazaki in view of Zhang et al. is applied as in the previous rejection but both references lack anticipation of a plastic substrate.

Kobayashi discloses that TFTs can typically be formed on plastic substrates (see column 7, lines 4-9). In view of this disclosure, it would have been obvious to one of ordinary skill in the art at the time the invention was made to form the device in Yamazaki et al. on a plastic substrate as taught by Kobayashi et al. because Kobayashi et al. discloses this to be typical device formation.

Claims 31-32 are rejected under 35 U.S.C. 103(a) as being unpatentable over Zhang, U.S. Patent 5,236,850 in view of Kobayashi et al., U.S. Patent 6,146,930.

Zhang is applied as in the previous office action but lacks anticipation of a plastic substrate.

Kobayashi discloses that TFTs can typically be formed on plastic substrates (see column 7, lines 4-9). In view of this disclosure, it would have been obvious to one of ordinary skill in the art at the time the invention was made to form the device in Zhang on a plastic substrate as taught by Kobayashi et al. because Kobayashi et al. discloses this to be typical device formation.

Claim 34 is rejected under 35 U.S.C. 103(a) as being unpatentable over Liu et al. in view of Zhang and further in view of Kobayashi et al., U.S. Patent 6,146,930 as applied to claims 15, 17-18, 33, 35-36, and 41-44 and further in view of Adachi et al..

Adachi et al. is applied as in the office action mailed 10-3-01 for the reasons of record.

Claim 38 is rejected under 35 U.S.C. 103(a) as being unpatentable over Yamazaki et al., U.S. Patent 5,773,227 in view of Zhang et al. and further in view of Kobayashi et al. as applied to claims 16, 19, 37, and 39-40 above, and further in view of Adachi et al..

Adachi et al. is applied as in the office action mailed 10-3-01 for the reasons of record.

Claim 45 is rejected under 35 U.S.C. 103(a) as being unpatentable over Zhang, U.S. Patent 5,236,850 in view of Kobayashi et al., U.S. Patent 6,146,930 as applied to claim 14 above, and further in view of Yamazaki, JP 4-177735.

Zhang and Kobayashi are applied as above but lack anticipation of forming a base film and a semiconductor film without outside exposure.

Yamazaki discloses forming an oxide and semiconductor film without exposure (see Figures and abstract). In view of this disclosure, it would have been obvious to one of ordinary skill in the art at the time the invention was made to form the base and semiconductor films in the primary reference without outside exposure because this reduces overall contamination.

Claim 46 is rejected under 35 U.S.C. 103(a) as being unpatentable over Liu et al., U.S. Patent 5,147,826 in view of Zhang, U.S. Patent 5,236,850 and further in view of Kobayashi et al., U.S. Patent 6,146,930 as applied to claims 15, 17-18, 33, 35-36, and 41-44 above, and further in view of Yamazaki, JP 4-177735.

Liu, Zhang, and Kobayashi are applied as above but lack anticipation of forming a base film and a semiconductor film without outside exposure.

Yamazaki discloses forming an oxide and semiconductor film without exposure (see Figures and abstract). In view of this disclosure, it would have been obvious to one of ordinary skill in the art at the time the invention was made to form the base and semiconductor films in the primary reference without outside exposure because this reduces overall contamination.

.Response to Arguments

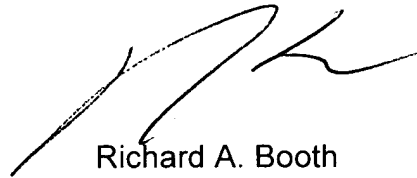
Applicant's arguments with respect to all of the claims have been considered but are moot in view of the new ground(s) of rejection.

Conclusion

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Richard A. Booth whose telephone number is 308-3446. The examiner can normally be reached on Monday-Thursday from 7:30-6:00.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, John Niebling can be reached on 308-3325. The fax phone numbers for the organization where this application or proceeding is assigned are 308-7724 for regular communications and 308-7724 for After Final communications.

Any inquiry of a general nature or relating to the status of this application or proceeding should be directed to the receptionist whose telephone number is 308-1782.



Richard A. Booth
Primary Examiner
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